

Zeiss

Merlin

Process Type: FA SEMs/TEMs/Dual Beams

Vintage: 2010

Equipment Information:

Status of Equipment: Refurbished

Specification:

Secondary electron image resolution:

0.8 nm @ 15kV

1.4 nm @ 1kV

0.6 nm @ 30kV STEM Mode

3.0 nm @ 20Kv at 10nA

WD = 8.5nm

Magnification: 12 – 2,000,000X

Specimen Stage:

Stage Motorization: 5 Axis Stage Motorization

X = 130mm, Y = 130mm, Z = 50mm, T = -3 to 70 deg, R = 360 deg

Configuration:

Operating System: Windows XP Pro

BSD

STEM

Load Lock

Motorized Stage

Smart SEM Version 5.07

Oxford EDX 50mm Sq detector
XEI Plasma Cleaner